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		TURING A MIC AND ETCH-STC	ROELECTRONIC	DEVICE USING	A REMOVABLE
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## METHOD OF FABRICATING A MICROELECTRONIC DEVICE

Inventors: Joseph J. Bendik Gerald T. Malloy Ronald M. Finnila

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#### ABSTRACT OF THE DISCLOSURE

A microelectronic device is fabricated by furnishing a first substrate (40) having a silicon 5 etchable layer (42), a silicon dioxide etch-stop layer (44) overlying the silicon layer (42), and a silicon wafer (46) overlying the single-crystal etch-stop layer (44), the wafer (46) having a front surface (52) not contacting the etch stop layer 10 A microelectronic circuit element (50) is (44).formed in the single-crystal silicon wafer (46). The method further includes attaching the front surface (52) of the single-crystal silicon wafer (46) to a second substrate (58), and etching away the silicon 15 layer (42) of the first substrate (40) down to the etch-stop layer (44). The second substrate (58) may also have a microelectronic circuit element (58') therein that can be electrically interconnected to the microelectronic circuit element (50).

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#### METHOD OF FABRICATING A MICROELECTRONIC DEVICE

## BV BACKGROUND OF THE INVENTION

This invention relates to microelectronic devices, and, more particularly, to a microelectronic device that is moved from one support to another support during fabrication.

Microelectronic devices are normally prepared by a series of steps such as patterning, deposition, implantation, growth, and etching that build up an 10 electronic circuit on or near the top surface of a thin substrate wafer. Interconnection pads are placed on the surface of the wafer to provide connections to external leads to or other microelectronic microelectronic devices. Such a 15 device is considered a two-dimensional structure in the plane of the substrate wafer. There are usually multiple layers of deposited conductors and insulators, but each layer is quite thin. Any height of the device in the third dimension perpendicular to 20 the substrate surface 15 much less than the dimensions in the plane of the substrate wafer, and is often no more than a few thousand Angstroms.

microelectronic devices or arrays of such The devices are usually placed inside a protective 25 housing called a package, with leads or connection extending out of the package. When pads the microelectronic devices are used, a number of the packages with their contained microelectronic devices normally affixed to a base such as a phenolic are plastic board. Wires are run between the various 30 devices to interconnect them. There may be metallic traces imprinted onto the base to provide common ground, and bus connections, and the base power. Such boards with a has external connections. itself

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